

Substitute for Form 1449 (P1) &amp; 1449 (P2)

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**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Application Number	10797046
Filing Date	March 11, 2004
First Named Inventor	Jung-hyun Lee et al.
Examiner Name	SARA W CRANE
Attorney Docket No.	1030681-000634

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**U.S. PATENT DOCUMENTS**

Examiner Initials	Document Number-Kind Code	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Passages or Figures Appear
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT LITERATURE DOCUMENTS**

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/O.N./	Sneh, Ofer et al., Thin film atomic layer deposition equipment for semiconductor processing, Thin Solid Films 402 (2002) 248-261
/O.N./	Copy of Office Action issued by Chinese Patent Office on March 21, 2007 for Chinese Patent Application No. 2004100283929
/O.N./	English Translation of Office Action issued by Chinese Patent Office on March 21, 2007 for Chinese Patent Application No. 2004100283929

Examiner Signature	/Ori Nadav/	Date Considered	11/05/2011
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